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2877

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

licant: Michael Weber-Grabau et al. PATENT APPLICATION

erial No.: 09/927,102

Group Art Unit: 2877

Filed: August 10, 2001

For: OPTICAL CRITICAL DIMENSION METROLOGY SYSTEM

INTEGRATED INTO SEMICONDUCTOR WAFER PROCESS TOOL

Supplemental Information Disclosure Statement with Certification under 37 CFR § 1.97(e) (1)

Hon. Commissioner for Patents Washington, D.C. 20231

Sir:

The following information is submitted in compliance with Applicants' duty of disclosure under 37

1.97(e). A copy of each reference is enclosed.

## U.S. PATENT DOCUMENTS

 Patent No.
 Patentee
 Grant Date

 5,233,191
 Noguchi, et al
 Aug. 3, 1993

 5,459,404
 Josephs
 Oct. 17, 1995

 5,994,914
 Tsuruta
 Nov. 30, 1999

## FOREIGN PATENT DOCUMENTS

Publication No.	Publ. Date	Country	<u>Translation</u>	
EP 0 991 918	April 12, 2000	EPO		
63 086429	April 16, 1988	Japan	Yes	

The undersigned hereby certifies that the items of information contained in this Supplemental Information Disclosure Statement were cited in a communication received from a foreign patent office in a counterpart foreign application not more than three months prior to the filing of this statement.

## CERTIFICATE OF MAILING

I hereby certify that this paper (along with any paper referred to as being attached or enclosed) is being deposited with the United States Postal Service on the date shown below with sufficient postage as first class mail in an envelope addressed to: Commissioner for Patents, Washington, D.C. 20231

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Respectfully submitted,

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U.S. PATENT DOCUMENTS													
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	AA	5,233,191	8/3/93	Noguchi et al.			250		306	4/2/91			
	AB	5,459,404	10/17/95	Josephs			324		751	3/28/94			
	AC	5,994,914	11/30/99	Tsuruta			324		765	7/25/97			
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